

## Abstract

The invention provides a micromechanical yaw rate sensor having: a substrate (100) having an anchoring device (21; 21') provided on the substrate; and an annular flywheel (10) that is connected, via a flexural spring system (30, 31; 32, 33), with the anchoring device (21; 21'; 25') in such a way that the area of connection with the anchoring device (21; 21'; 25') is located essentially in the center of the ring, so that the annular flywheel (10) is able to be displaced, elastically from its rest position, about an axis of rotation (z) situated perpendicular to the substrate surface, and about at least one axis of rotation (y) situated parallel to the substrate surface. The anchoring device (21; 21'; 25') has two bases (21; 21') that are situated opposite one another and are connected fixedly with the substrate (100), connected with one another via a bridge (25'). A V-shaped flexural spring (30, 31; 32, 33) of the flexural spring system (30, 31; 32, 33) is attached to each of the opposite sides of the bridge (25') in such a way that the apex is situated on the bridge (25') and the limbs are spread towards the flywheel (10) with an opening angle.

(Figure 1)